IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant:

Kiyoshi Arita

Serial No.:

TBD

Art Unit: TBD

Filing Date:

Herewith

Title:

METHOD OF MANUFACTURING SEMICONDUCTOR DEVICE, PLASMA

PROCESSING APPARATUS AND PLASMA PROCESSING METHOD

Docket No.:

36280

INFORMATION DISCLOSURE STATEMENT

Mail Stop PATENT APPLICATION Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

In accordance with Rule 56, applicant is aware of the publications listed in the enclosed copy of Patent Office Form 1449. A copy of each of the publications is enclosed herewith.

Respectfully submitted,

PEARNE & GORDON LLP

Bv:

US 144

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Date: November 19, 2003

Form PTO-1449

U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE

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INFORMATION DISCLOSURE CITATION BY APPLICANT

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		Document No.	Date	Country		Class	Subclass	Translation
	М	2002-93752	3/2002	JР				Cited in Specification
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OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, Etc.)								
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